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OFFICIAL

RESPONSE UNDER 37 CFR § 1.116 EXPEDITED PROCEDURE EXAMINING GROUP 2813

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):

Jack O. Chu, et al.

Examiner:

E.J. Kielin

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Dated: May 4, 2004

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

RESPONSE UNDER 37 C.F.R. § 1.116

Sir:

In response to the Office Action dated March 4, 2004, applicants submit the following amendments and remarks for entry of record in the above-identified patent application.

CERTIFICATION OF FACSIMILE TRANSMISSION

I hereby certify that this paper is being facsimile transmitted to the Patent and Trademark Office on the date shown below.

Dated: May 4, 2004

Leslie S. Szivos, Ph.D.

1

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